

Docket No. 201413US-2 PCT

IN RE APPLICATION OF: TAKASHI MIYACHI

SERIAL NO: 09/720,789

FILED: DECEMBER 29, 2000

FOR: SCANNING EXPOSURE METHOD, SCANNING EXPOSURE APPARATUS...



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ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

Transmitted herewith is an amendment in the above-identified application.

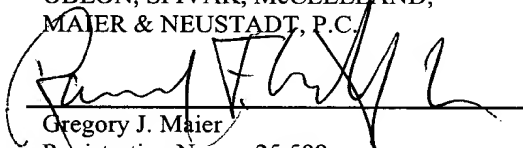
- ☐ No additional fee is required
- ☐ Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.
- ☒ Additional documents filed herewith: MARKED-UP COPY, PETITION FOR EXTENSION OF TIME (1 MONTH)

The Fee has been calculated as shown below:

CLAIMS	CLAIMS REMAINING		HIGHEST NUMBER PREVIOUSLY PAID	NO. EXTRA CLAIMS	RATE	CALCULATIONS
TOTAL	30	MINUS	47	0	× \$18 =	\$0.00
INDEPENDENT	4	MINUS	4	0	× \$84 =	\$0.00
		<input type="checkbox"/> MULTIPLE DEPENDENT CLAIMS				+ \$280 = \$0.00
		TOTAL OF ABOVE CALCULATIONS				\$0.00
		<input type="checkbox"/> Reduction by 50% for filing by Small Entity				\$0.00
		<input type="checkbox"/> Recordation of Assignment				+ \$40 = \$0.00
		TOTAL				\$0.00

- ☒ A check in the amount of **\$110.00** is attached.
- ☒ Please charge any additional Fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.
- ☒ If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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201413US-2 PCT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

:

TAKASHI MIYACHI

: EXAMINER: NGUYEN, H.

SERIAL NO.: 09/720,789

: GROUP ART UNIT: 2851

FILED: DECEMBER 29, 2000

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FOR: SCANNING EXPOSURE  
METHOD, SCANNING  
EXPOSURE APPARATUS...

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#10/a  
11-21-02  
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AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

Responsive to the Official Action dated July 19, 2002, please amend the above  
identified application as follows:

IN THE CLAIMS

Please amend Claims 1, 3-15, 23-25 and 30 as shown in the attached marked-up copy  
to read as follows:

1. (Amended) A scanning exposure method for transferring a pattern formed on a  
mask to a divided area on a substrate through a projection optical system, said scanning  
exposure method comprising the steps of:

determining a surface condition of the divided area;

deciding to use either a first focusing control mode providing substrate tilt changing  
control or a second focusing control mode maintaining substrate tilt unchanged as a decided